IN THE U.S. PATENT AND TRADEMARK OFFICE

Application No.:	10/519,700)
Filing Date:	September 14, 2005)
Inventor(s):	Krull))
Group Art Unit:	1765)
Examiner Name:	Angadi,Maki A)
Customer No.:	27160)
Confirmation No.:	6925)
Title: ION IMPLANTATION ION SOURCE, SYSTEM AND METHOD)

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Official Action, mailed on January 8, 2007, please enter the following preliminary amendment.

Amendments to the Specification are reflected on page 2 of this paper.

Remarks begin on page 11 of this paper.